

AR / DFW



Attorney Docket No.: 0553-0152.02

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Shunpei YAMAZAKI et al.

Serial No.: 10/684,936

Filed: October 14, 2003

For: Semiconductor Device And Method
Of Fabricating The Same

Examiner: Thien F. Tran

Art Unit: 2811

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Name of applicant, assignee, or Registered Rep.

Shannon Wallace 7/11/05

Signature

Date

Commissioner for Patents
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Alexandria, VA 22313-1450

RESPONSE B (AFTER FINAL)

Applicants have the following response to the Final Rejection of April 5, 2005, a one month extension of time being submitted herewith. Applicants will address each of the Examiner's rejections in the order in which they appear in the Final Rejection.

Claim Rejections - 35 USC §112

In the Final Rejection, the Examiner rejects Claims 81-85 under 35 USC §112, first paragraph, as failing to comply with the written description requirement. This rejection is respectfully traversed.

In particular, the Examiner contends that the "recitation of an electrode through the first silicon nitride oxide film and the second silicon nitride oxide film sets forth a structure not supported